in a shape of an undivided wafer to be split into separate fluid jetting apparatuses,

wherein

the heat driving part includes fluid chambers for corresponding fluid jetting apparatuses, and

the membrane separates the fluid chambers of the heat driving part from the nozzle part.

E1

17. (FOUR TIMES AMENDED) A process of manufacturing a plurality of fluid jetting apparatuses at once, comprising:

forming a nozzle part on a silicon wafer by a spinning process;

adhering the nozzle part with the silicon wafer to a membrane;

removing the silicon wafer from the nozzle part; and

E2

adhering the membrane with the adhered nozzle part to a heat driving part such that the membrane is between the heat driving part and the nozzle part to form the fluid jetting apparatuses as an undivided unit.

E3

23. (TWICE AMENDED) The process of manufacturing a plurality of fluid jetting apparatuses as claimed in claim 17, further comprising forming the heat driving part, the forming the heat driving part comprising:

forming electrodes and heat elements on a substrate of another silicon wafer;

forming driving fluid barriers on the electrodes and the heat elements; and

forming driving fluid chambers between corresponding pairs of the driving fluid barriers with the electrodes and the heat elements forming bottom sides of the corresponding driving fluid chambers, each of the bottom sides being between the corresponding pair of the driving fluid barriers.